

Application Data Sheet

Application Information

Application Type:: National Phase
Subject Matter:: Utility
CD-ROM or CD-R:: None
Title:: WAFER DOUBLE-SIDE POLISHING
APPARATUS AND DOUBLE-SIDE POLISHING
METHOD
Attorney Docket Number:: 120214
Suggested Drawing Figure::
Total Drawing Sheets:: 10
Small Entity:: No

Applicant Information

Applicant Authority type:: Inventor
Primary Citizenship Country:: Japan
Status:: Full Capacity
Given Name:: Hiroyoshi
Family Name:: TOMINAGA
City of Residence:: Fukushima
Country of Residence:: JAPAN

Applicant Authority type:: Inventor
Primary Citizenship Country:: Japan
Status:: Full Capacity
Given Name:: Toshiyuki
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City of Residence:: Gunma
Country of Residence:: JAPAN

Correspondence Information

10 / 500278

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Correspondence Customer Number:: 25944

Domestic Priority Information			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	National Stage of	PCT/JP03/03743	3/26/2003
Foreign Priority Information			
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2002-91087	3/28/2002	Yes
Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2002-91207	3/28/2002	Yes
Assignee Information			
Assignee Name::	SHIN-ETSU HANDOTAI CO., LTD.		
Street of mailing address::	4-2, Marunouchi 1-chome, Chiyoda-ku,		
City of mailing address::	Tokyo,		
Country of mailing address::	JAPAN		